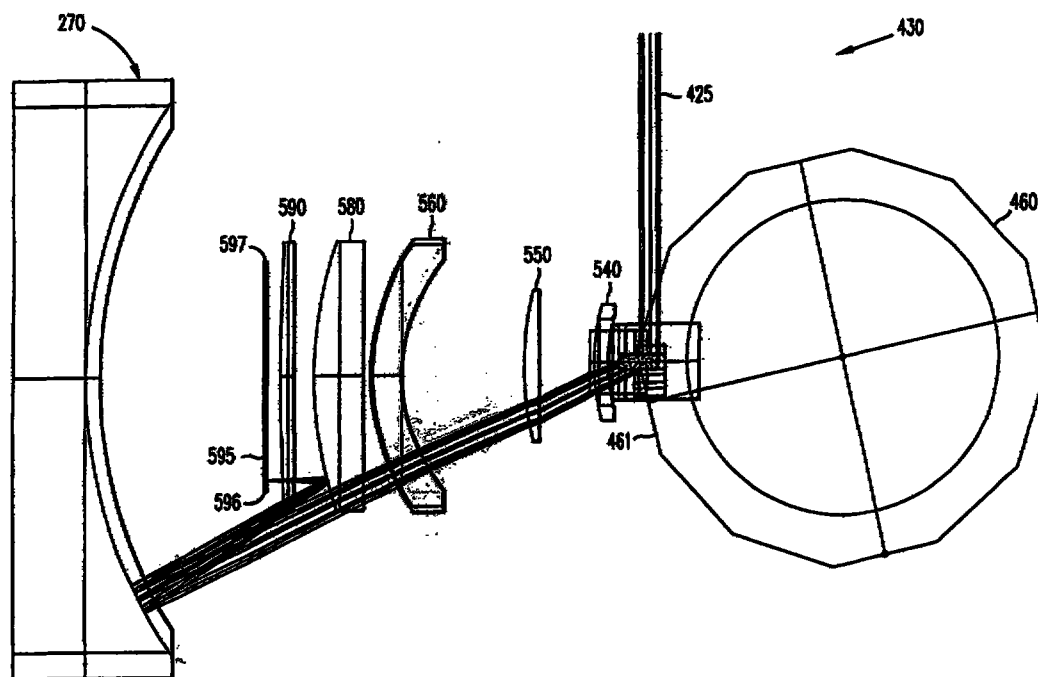




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(54) Title: ANAMORPHIC SCAN LENS FOR LASER SCANNER



(57) Abstract

An anamorphic, catadioptric scan lens simultaneously corrects for distortion, polygon mirror wobble, and flat-field telecentric scanning of polychromatic laser light that is injected sagittally onto the polygon mirror. This system is also capable of imaging multiple beams and is corrected for differential distortion. The scan lens is incorporated in a photolithographic image scanner.